

***Amendments to the Claims***

This listing of claims will replace all prior versions, and listings of claims in the application.

Claims 1-36 (cancelled)

37. (Currently Amended) A method for manufacturing an electromechanical transducer ~~comprising a ferroelectric thin film sandwiched between an top electrode and a bottom electrode~~, comprising the steps of:

forming an adhesive metal layer composed of an adhesive metal over the surface where said transducer is installed;

forming a first anti-diffusion metal layer composed of an anti-diffusion metal over said adhesive metal layer;

forming a ~~said~~ bottom electrode over said anti-diffusion metal layer;

forming a second anti-diffusion metal layer composed of said anti-diffusion metal over said bottom electrode; and

forming a baking said ferroelectric thin film while this ferroelectric thin film is formed over said second anti-diffusion metal layer, and baking said ferroelectric thin film while it is formed, and thereby diffusing said adhesive metal all the way to said second anti-diffusion metal layer and producing an anti-diffusion layer at the location of said second anti-diffusion metal layer promoting the alloying of said anti-diffusion metal and said bottom electrode, and producing an adhesive layer at the location of said adhesive metal layer and first anti-diffusion metal layer.

38. (Original) The method for manufacturing a electromechanical transducer according to claim 37, wherein a metal selected from the group consisting of iridium, palladium, rhodium, ruthenium, and osmium is used as the anti-diffusion metal.

39. (Original) The method for manufacturing a electromechanical transducer according to claim 37, wherein either titanium or chromium is used as said adhesive metal.

Claims 40-51 (cancelled).